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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

App. No. : 10/689,402 : Confirmation No.: 2570  
Applicant : Peng Zhang et al.  
Filed : 10/20/2003  
For : PROCESS SOLUTIONS CONTAINING SURFACTANTS USED AS  
POST-CHEMICAL MECHANICAL PLANARIZATION TREATMENT

Art Unit : 1746  
Examiner : B. S. Carrillo

Docket No. : 06412 USA  
Customer No. : 23543

Commissioner for Patents  
P.O. Box 1450  
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Amendment and Response

Sir:

The following is responsive to the Office Action dated April 29, 2005:

- ☐ Amendments to the Specification begin on page \_\_\_\_\_ of this paper.
- ☒ Amendments to the Claims are reflected in the listing of claims which begins on page 2 of this paper.
- ☐ Amendments to the Drawings begin on page \_\_\_\_\_ of this paper and include an attached replacement sheet(s).
- ☐ Amendments to the Abstract are on page \_\_\_\_\_ of this paper. A clean version of the Abstract is on page \_\_\_\_\_ of this paper.
- ☒ Remarks/Arguments begin on page 10 of this paper.

OK to  
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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE  
PATENT EXAMINING OPERATION

**Applicant(s):** Peng Zhang et al.

**Serial No.:** 10/689,402

**Group Art Unit:** 1746

**Filed:** 20 October 2003

**Examiner:** B. S. Carrillo

**Atty. Docket No.:** 06412 USA

**Confirmation No.:** 2570

**For:** PROCESS SOLUTIONS CONTAINING SURFACTANTS USED AS POST-CHEMICAL MECHANICAL PLANARIZATION TREATMENT

DECLARATION UNDER 37 C.F.R. § 1.132

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir:

*OK to  
allow  
pgs  
8/1/05*

I, Peng Zhang, Ph.D., a citizen of the Republic of China hereby declare and state:

1. I have a Bachelor's of Science in Chemical from Peking University of China, a Masters in Science in Polymer Chemistry from Peking University of China, and a Doctorate in Organic Chemistry from the University of Illinois at Urbana-Champaign.
2. I am currently employed by Air Products and Chemicals, Inc. (APCI), the assignee of the present application. I have worked as a Senior Principle Research Chemist with APCI for approximately seven years. In my present assignment, I am the technology leader in photoresist ancillary and immersion lithograph programs and am responsible for developing new photoresist developers and surface conditioner products. I have also provided technical consultation on various research programs such as supercritical carbon dioxide process solutions, post chemical mechanical planarization (CMP) cleaning, post-etch and/or ash cleaning, and photoresist stripping.
3. I am an inventor on the present application, 10/689,402, along with Brenda Faye Ross.